HIGH-PRESSURE GAUGES WITH ELECTRIC SENSORS

by

E.CZAPUTOWICZ, J.JANKOWSKI, M.ŁAPIŃSKI, R.WIŚNIEWSKI W.WŁODARSKI

Poland

Basic Parameters of a Secondary High-pressure Sensor

If \mathcal{X} is the given physical property, the basic parameters of the secondary high-pressure sensor are [1]:

 $\begin{aligned} &\mathcal{L}_{\mathcal{H}} = \left[\frac{\partial \mathcal{L}}{\partial \mathcal{L}_{\mathcal{H}}} \frac{\partial \mathcal{P}}{\partial \mathcal{P}} \right]_{\mathrm{T}} & - \text{ pressure sensitivity coefficient;} \\ & \int_{\mathcal{H}} \frac{\partial \mathcal{P}}{\partial \mathcal{L}_{\mathcal{H}}} = \left[\frac{\partial \mathcal{R}}{\partial \mathcal{L}_{\mathcal{H}}} \frac{\partial \mathcal{P}}{\partial \mathcal{T}} \right]_{\mathrm{P}} & - \text{ temperature sensitivity coefficient;} \\ & \int_{\mathcal{H}} \frac{\partial \mathcal{P}}{\partial \mathcal{L}_{\mathcal{H}}} = \left(\frac{\partial \mathcal{P}}{\partial \mathcal{T}} \right)_{\mathcal{H}} & - \text{ temperature coefficient of the } \\ & \text{ pressure reading shift;} \end{aligned}$

 $z_{\chi} = \mathcal{L}_{\chi} / \mathcal{J}_{\chi} = \mathcal{L}_{\chi}^{2} / \mathcal{J}_{\chi}$ - coefficient of pressure quality. The last coefficient, introduced by Czaputowicz [2] seems to be the best indicator of the suitability of a given physical property of a sensor for high-pressure measurements. It is important that the absolute value of the coefficient of pressure quality $|z_{\chi}|$ be possibly high. In the present paper only electric properties will be discussed. All values of pressure are given in atmospheres, where:

1 atm = 1 kg/cm² = 0.0980665 MN/m²

High-pressure Resistance Gauges with Metal Sensors

The manganin sensor is one of the most populare resistance metal sensors for measurements of high pressures [3]. The relative change of electric resistivity with increasing pressure and temperature for Russian and German manganin is diagramatically presented in Fig.1

In the range up to 6000 atm $\propto = \left[\partial R/(R_0 \partial P) \right]_T$ decreases linearly with the growing pressure:

$$\alpha c_{\rm P} = \alpha c_{\rm O} + \alpha c_{\rm O} \cdot P \tag{1}$$

where \ll_{o} dependes on the kind of wire, its diameter, and heat treatment [2]. At room temperatures we have:

- 1 -

PO-297

 $\alpha_0 = (2.0 - 2.6) \times 10^{-6} \text{ atm}^{-1}$ $\alpha_1 \approx -5 \times 10^{-12} \text{ atm}^{-2}$

For two kinds of wire \mathcal{L}_0 increases with growing temperature (cf. Fig.1) where

$$\delta = [\partial \alpha_0 / (c_0 \partial T)]_P = 1 \times 10^3 \text{ deg}^{-1}$$

but $c_1 \approx \text{const.}$ in the range 15 to 30°C.

In the range 6000 to 16,000 atm. c_P also decreases linearly with growing pressure (Fig.2) but at a rate about half that observed up to 6000 atm. The relative variations of resistivity with growing temperature are given for all manganin wires by the following parabolic function [3]:

$$\Delta R/R_{20} = at^2 + bt + c \qquad (2)$$

where a,b,c depend on the kind of wire, heat treatment and the range of pressures (Table 1).

Czaputowicz constructed a new kind of manganin sensor consisting of two kinds of wire, Russian and German, connected in series. In this sensor $\beta = \left[\frac{\partial R}{(R_o \partial T)}\right]_P$ is about ten times less than in the standard Russian, English or German manganin wires in the temperature range 17 to 27°C and the maximum error in the pressure reading due to temperature variation is only 2 atm. It allows for measuring both relatively small pressures (up to 1000 atm) and dynamic pressures [4].

High-pressure Resistance Gauges with Semiconductor Sensors The application of pure (non-doped) semiconductor crystals of Te and InSb as high-pressure sensors was discussed by the present authors at the IMEKO-IV Conference [1]. However, since in practice all semiconductor materials are contaminated, it seems justified to express the basic parameters of the semiconductor resistive sensor by the value of the effective energy gap E^{\pm} and the effective energy gap pressure coefficient $a^{\pm} = (\partial E^{\pm}/\partial P)_{\mp}$ which fulfil the equation:

 $R/R_{o} = \exp \left(E^{H} - a^{H}P\right)/(2kT)$ (3)

- 2 -

PO-297